Search Notes				

Application/Control No.	Applicant(s)/Patent under Reexamination
10/669,220	LIU ET AL.
Examiner	Art Unit
Jim Vannucci	2828

	SEARCHED				
Class	Subclass	Date	Examiner		

INTERFERENCE SEARCHED			
Subclass	Date	Examiner	
	T I		

SEARCH NOT (INCLUDING SEARCH)
	DATE	EXMR
via, through hole, ion implant, vertical cavity laser	8/2/2005	JV .